

# Synthesis of Ammonia Using CH<sub>4</sub>/N<sub>2</sub> Plasmas Based on Micro-Gap Discharge under Environmentally Friendly Condition

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**Abstract** The synthesis of ammonia has been studied in methane-nitrogen plasmas using a micro-gap discharge under an environmentally friendly condition. The effects of some parameters such as the specific input energy, the discharge gap, the volume ratio of CH<sub>4</sub>/N<sub>2</sub>, the residence time, and the gas temperature on the yield of NH<sub>3</sub> and conversion rate of CH<sub>4</sub> are discussed in the paper. The results show that the highest yield of NH<sub>3</sub> is 8000 ppm for a residence time of 1.6 s. In addition, the yield and generating rate of H<sub>2</sub> are 9.1% (v/v) and 1879.8 μmol/min, respectively. Therefore, the micro-gap discharge is an efficient method for NH<sub>3</sub> synthesis and H<sub>2</sub> generation from CH<sub>4</sub>.

**Keywords** Concentration of synthesized NH<sub>3</sub> · Conversion rate of CH<sub>4</sub> · Micro-gap discharge · Environmentally friendly condition

## Introduction

Ammonia (NH<sub>3</sub>), as an important chemical product, can be used to produce ammonium fertilizer, such as carbamide ammonium nitrate and ammonium bicarbonate. Hydrogen (H<sub>2</sub>) is definitely a green energy source, and hydrogen based fuel-cell technology has been investigated extensively to develop fuel cell vehicles and cogeneration system. Methane is the major constituent of natural gas. Activation of saturated hydrocarbons and especially methane is difficult due to the high dissociation energy of C–H bonds. The direct synthesis of NH<sub>3</sub> using CH<sub>4</sub> rather than H<sub>2</sub> by non-equilibrium plasma at atmospheric pressure is of great importance.

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A number of studies on plasma synthesis of ammonia have been carried out by radio frequency (=13.56 MHz) or microwave (=2540 MHz) discharge at low pressure. In 1994, Oumghar, Legrand et al. [1–3] investigated the conversion of  $\text{CH}_4$  by  $\text{N}_2$  or air microwave plasma, as well as kinetic mechanism of  $\text{CH}_4$  conversion.  $\text{C}_2$  hydrocarbons ( $\text{C}_2\text{H}_2$ ,  $\text{C}_2\text{H}_4$ ,  $\text{C}_2\text{H}_6$ ) and trace amount of  $\text{HCN}$ ,  $\text{NH}_3$  were obtained, and the methane conversion rate was 80% within the power range of 350~650 W. Some studies [4, 5] reported that ammonia molecules would be formed by the reaction between  $\text{NH}_x$  radicals and hydrogen atoms. In some cases, catalysts were placed in the discharge or afterglow region, or on the cold trap wall in order to enhance the ammonia yield [5–8]. Tanaka et al. [7, 8] studied the synthesis of ammonia in  $\text{N}_2$ - $\text{H}_2$  plasmas by microwave or radio frequency discharge at a pressure of 650 Pa (5 Torr) with catalysts of iron and molybdenum wires of 100 pieces. The yields of  $\text{NH}_3$  and  $\text{N}_2\text{H}_4$  were only 1.5 mmol/g and 2.5  $\mu\text{mol/g}$ , respectively, with a residence time of 2 h and power input of 180 W. The main drawback of low pressure plasmas is low energy efficiency and low yields of  $\text{NH}_3$ .

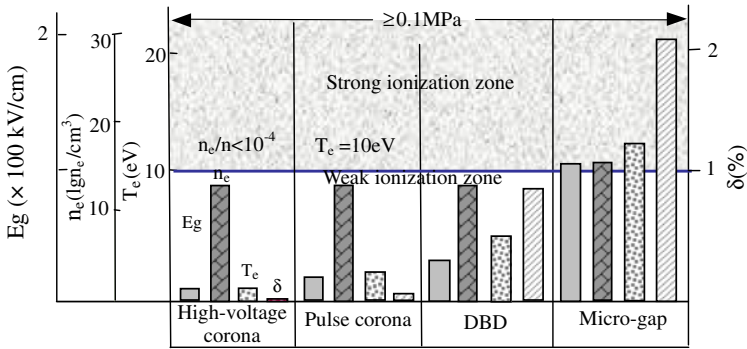
$\text{H}_2$  generation from water, methane, and methanol was investigated in a ferroelectric pellet packed-bed reactor (FPR) and a silent-discharge-type reactor (SDR) by Kabashima et al. [9] in 2003. The  $\text{H}_2$ -generation rate with FPR was 54  $\mu\text{mol/min}$  in ambient Ar. Suid et al. [10] have reported water splitting by a dielectric barrier discharge (DBD) plasma reactor, of which the inner electrode was an Au-coated copper rod. The highest  $\text{H}_2$ -generating rate was 3.4  $\mu\text{mol/min}$  in ambient Ar.

In previous studies performed by the author, the  $\text{NH}_3$  synthesis in  $\text{N}_2$ - $\text{H}_2$  plasmas was carried out using the combined surface discharge and DC (direct current) discharge [11].  $\text{NH}_3$  yield was 5000 ppm with  $\text{MgO}$  catalyst. Subsequently, the concentration of  $\text{NH}_3$  reached 12500 ppm by the micro-gap DBD without any catalyst [12, 13]. In this paper, the synthesis of  $\text{NH}_3$  by  $\text{N}_2$ - $\text{CH}_4$  plasmas was performed. The yield of  $\text{NH}_3$  was 8000 ppm for a residence time of 1.6 s. The whole process was carried out under atmospheric pressure without any catalyst, which is an environmentally friendly condition in line with Green Chemistry Principle [14, 15].

## Plasma Processes of Micro-Gap Discharge

### Comparison of Main Parameters between Several Kinds of Gas Discharges

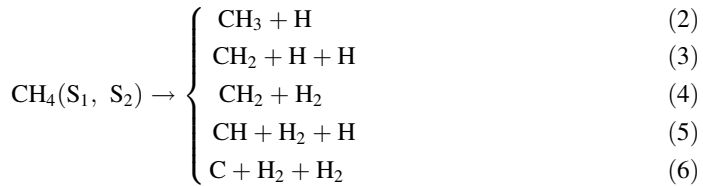
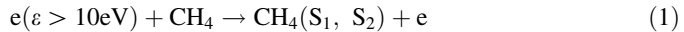
The comparison of main parameters between several kinds of gas discharges is shown in Fig. 1. At high pressure ( $\geq 10^5$  Pa), the main gas discharges are the high-voltage corona, pulse corona, general DBD, and our micro-gap discharge. Strong and weak ionization zones are separated by the line which is defined by the following parameters: the electric field intensity  $E_g$ , 100 kV/cm; the electron density in discharge path  $N_e$ ,  $10^{14}/\text{cm}^3$ ; the average electron energy  $T_e$ , 10 eV; and the fractional active volume ( $\delta$ , %), 1%. The main parameters of our micro-gap discharge, which falls in the strong ionization zone, are much higher than that of other gas discharges; in particular the fractional active volume is about 2%. The fractional active volume refers to the volume ratio of the volume of all ionization discharge paths to that of micro-gap. Plasma chemistry reactions take place in the ionization discharge paths. The increase of the fractional active volume leads to more discharge paths, resulting in greater whole electron density in the micro gap. Therefore, our micro-gap discharge is an efficient method for the conversion of  $\text{CH}_4$  into  $\text{NH}_3$ .



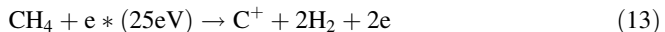
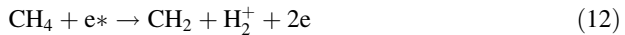
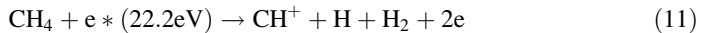
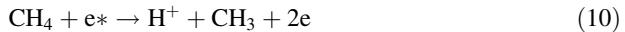
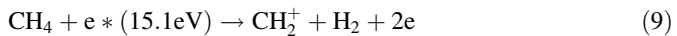
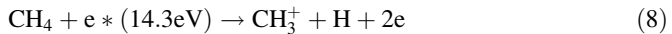
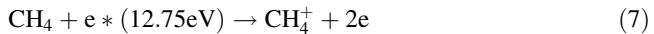
**Fig. 1** Comparison of main parameter for several kinds of gas discharge

### Excited Dissociation, Direct Ionization of CH<sub>4</sub> and Formation of H<sub>2</sub>

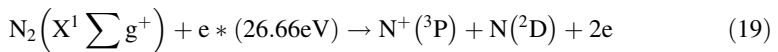
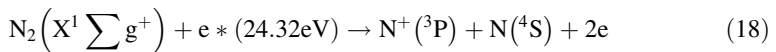
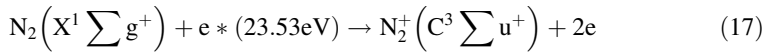
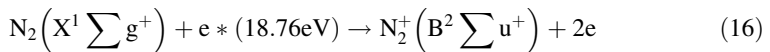
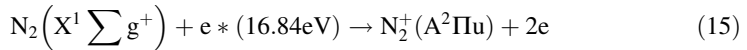
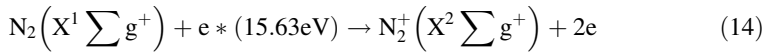
The dissociative potential of C–H bond of CH<sub>4</sub> is less than 4.6 eV. The excited methane S<sub>1</sub> (9.6 and 10.4 eV) and S<sub>2</sub> (11.7 eV), which are formed by the electron-methane collisions, are so unstable that rapidly dissociate into radicals such as CH<sub>3</sub>, CH<sub>2</sub>, CH, C. The plasma reactions are as follows [1–3]:



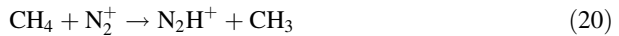
Direct Ionizations of CH<sub>4</sub> are as follows [12]:



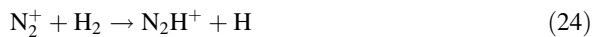
T<sub>e</sub> in our micro-gap discharge is  $\geq 10$  eV, which means a lot of electrons have the energy  $\geq 9.6$  eV. In this study, the above plasma reactions might be dominant reactions for H<sub>2</sub> generation as well as the formations of CH<sub>4</sub>, CH<sub>3</sub>, CH<sub>2</sub>, CH radicals and CH<sub>4</sub><sup>+</sup>, CH<sub>3</sub><sup>+</sup>, CH<sub>2</sub><sup>+</sup> ions.

Dissociation and Ionization of N<sub>2</sub> Molecule [16]Plasma Processes of NH<sub>3</sub> Synthesis

The CH<sub>4</sub>, CH<sub>3</sub> etc. react with N<sub>2</sub><sup>+</sup>, N<sup>+</sup>, N(<sup>4</sup>S) to form the NH radicals as follows [1, 2]. Ion reactions (20) with high rate constant are the major reactions.



NH radicals, which are considered as the ammonia precursors, are formed by the reactions of N<sub>2</sub><sup>+</sup> with H<sub>2</sub>, H. Also N atoms adhered to the wall react with hydrogen to form NH radicals [1, 2, 12].

Synthesis of NH<sub>3</sub> molecule [12]

The N<sub>2</sub><sup>+</sup> ion is the major activated particle to form the NH radical and leads to NH<sub>3</sub>. As for the micro-gap discharge, a lot of electrons have the energy ≥ 15.6 eV (ionization potential of N<sub>2</sub>). Therefore, the micro-gap discharge is an efficient plasma method for the synthesis of NH<sub>3</sub> at atmospheric pressure.

## Experiment

### Experimental Setup

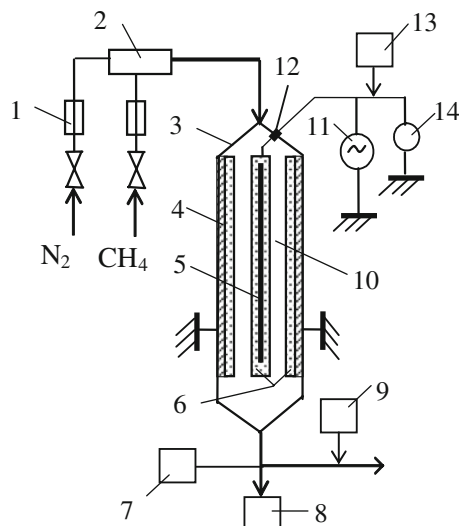
The experimental setup for synthesis of  $\text{NH}_3$  using the micro-gap discharge is shown in Fig. 2. The plasma reactor 3 is rectangular, of which the dimension is 260 mm (length)  $\times$  130 mm (width)  $\times$  35 mm (thickness). The thin dielectric layers of  $\alpha\text{-Al}_2\text{O}_3$  are attached to both sides of discharge electrodes, of which the dimension is 175 mm (length)  $\times$  80 mm (width)  $\times$  0.3 mm (thickness). The discharge gap is 0.47 mm or 0.64 mm. The dielectric constant and the electric insulation intensity are 10 and 350 kV/cm, respectively. With this thin dielectric layer, strong streamer discharge can be obtained in the micro-gap.

### Measurement System

The  $\text{CH}_4\text{-N}_2$  gas mixture with a purity of 99.98% is fed into the reactor. The gas flow rate and mixing ratio are adjusted by the mass-flow controller 4000 Series Gas Mixing System (Enviroincs INC in USA). The yield of ammonia is monitored on-line by GXH-105 Type Infrared Analyzer. The feed and product of gaseous hydrocarbons are analyzed with a gas chromatograph of GC-102 or HP4890 equipped with a thermal conductivity detector (TCD) and a flame ionization detector (FID). The relative standard deviation (RSD) is  $<0.5\%$  based on the five times measurement of one sample.

The self-made power supply is applied to the discharge electrodes, leading to a continuous strong streamer discharge, of which the main parameters are as follows: the discharge power, 240 W; the applied frequency, 10 kHz; the pulse width, 40  $\mu\text{s}$ . The electric parameters are measured using HV-60 High Voltage Probe (Iwatsu, Japan), SS-240 Pulse Current Probe (Iwatsu, Japan), TDS-3032B Oscilloscope (Tektronix, USA), Model HC-F1000L Frequency Meter (Hong Chong Electronic Co. Ltd) and Q3-V Electrostatic Voltage Meter (Beijing Electric Meter Factory, China).

**Fig. 2** Schematic diagram for the synthesis of  $\text{NH}_3$  by  $\text{CH}_4\text{-N}_2$  plasmas Note: 1. Gas flow meter; 2. Gas mixing system; 3. Plasma reactor; 4. Earthing electrode 5. Discharge electrode 6. Dielectric layers; 7.  $\text{NH}_3$  analyzer; 8. Glass for Liquid fuel; 9. Gas chromatograph; 10. Discharge gap; 11. Power supply; 12. Insulator 13. Oscillograph; 14. Electrostatic voltage meter



## Evaluation of System Performance

In order to evaluate the energy efficiencies for methane conversion, the specific input energy (SIE, electrical input energy to unit volume of gas), defined in Eq. 1, is used. The discharge power is measured using the method of charge-voltage figure [17, 18], which can efficiently eliminate the measure error caused by discharge gap that was equal to a capacitor. Equations 2–3 indicate the calculation methods for generation rate and conversion rate of CH<sub>4</sub>. The volume per mol in our experiments is 24.2 L/mol with a temperature of 22°C and an atmospheric pressure.

$$1. \text{ Specific input energy} = \frac{\text{Discharge power}}{\text{Flow rate feed gas}} \quad (\text{J/L}) \quad (1)$$

$$2. \text{ Generation or conversion rate} = \frac{\text{Yield (v/v)} \times \text{Flow rate}}{\text{Volume per mol}} \quad (\mu\text{mol/min}) \quad (2)$$

$$3. \text{ Methane conversion} = \frac{\text{Consumed CH}_4}{\text{Initial CH}_4} \times 100(\text{mol}\%) \quad (3)$$

## Experimental Results

### Analysis of Gaseous Products for the Conversion of CH<sub>4</sub>

The experiments were carried out at 22°C, 10<sup>5</sup> Pa, without any catalyst. The mixed gases of CH<sub>4</sub>/N<sub>2</sub>=3:1 (v/v) were fed into the reactor at a flow rate of 0.5 L/min. The specific input energy (SIE) is 29.2 kJ/L with a discharge power of 243.6 W. The discharge gap width of the plasma reactor is 0.47 mm. The yields of gaseous products in Table 1 were analyzed with a GC-102 gas chromatograph by Institute of Guang Ming Chemical Engineering. The standard gases of hydrocarbons, NH<sub>3</sub> and H<sub>2</sub> were injected into the Chromatogram to calibrate their peak values.

As shown in Table 1, hydrocarbons ( $\leq C_4$ ) such as ethane (C<sub>2</sub>H<sub>6</sub>), ethylene (C<sub>2</sub>H<sub>4</sub>), acetylene (C<sub>2</sub>H<sub>2</sub>), propane (C<sub>3</sub>H<sub>8</sub>), propylene (C<sub>3</sub>H<sub>6</sub>), butane (i-C<sub>4</sub>H<sub>10</sub>, n-C<sub>4</sub>H<sub>10</sub>) are produced by electron collision reaction and recombination reaction. The yield and generation rate of hydrocarbons are of the following relationship C<sub>2</sub>H<sub>6</sub> > C<sub>3</sub>H<sub>8</sub> > C<sub>2</sub>H<sub>2</sub> > C<sub>2</sub>H<sub>4</sub> > i-C<sub>4</sub>H<sub>10</sub>, n-C<sub>4</sub>H<sub>10</sub> > C<sub>3</sub>H<sub>6</sub>. 10.13% of the residual is not identified, which is possibly to be gaseous hydrocarbon ( $\geq C_5$ ). The conversion rate of CH<sub>4</sub> is 4752  $\mu\text{mol/min}$ .

With the electron-methane collisions, large numbers of H<sub>2</sub> are produced by exited dissociation and direct ionization of CH<sub>4</sub>. The yield and generation rate of H<sub>2</sub> are 9.1%

**Table 1** Data for the conversion of CH<sub>4</sub> into hydrocarbons ( $\leq C_4$ ), NH<sub>3</sub> and H<sub>2</sub>

Item	CH <sub>4</sub>	H <sub>2</sub>	C <sub>2</sub> H <sub>6</sub>	C <sub>2</sub> H <sub>4</sub>	C <sub>2</sub> H <sub>2</sub>	C <sub>3</sub> H <sub>8</sub>	C <sub>3</sub> H <sub>6</sub>	i-C <sub>4</sub> H <sub>10</sub>	n-C <sub>4</sub> H <sub>10</sub>	NH <sub>3</sub>	Total	Products ( $\geq C_5$ )
Yield (v/v %)	52	9.1	1.7	0.16	0.24	0.6	0.04	0.12	0.11	0.8	64.87	10.13
Generation or conversion rate ( $\mu\text{mol}/\text{min}$ )	4752	1879.8	351.2	33.1	49.6	123.9	8.26	24.79	22.72	165.1		

The yields of gaseous products were tested by Institute of Guang Ming Chemical Engineering

(v/v) and 1879.8  $\mu\text{mol}/\text{min}$ , respectively. These data show that the micro-gap discharge is a promising method to obtain high  $\text{H}_2$ -generating rate in the absence of catalyst.

The  $\text{NH}_3$  is synthesized by atmospheric plasma in ambient  $\text{N}_2$  and  $\text{CH}_4$ . The yield of synthesized  $\text{NH}_3$  is 8000 ppm equal to 0.42 mmol/g for a residence time of 1.6 s. The yield of  $\text{NH}_3$  would be  $1.89 \times 10^3$  mmol/g if the gas residence time was 2 h. However, the yield of  $\text{NH}_3$  was only 1.5 mmol/g for a residence time of 2 h by Tanaka et al. [7, 8].

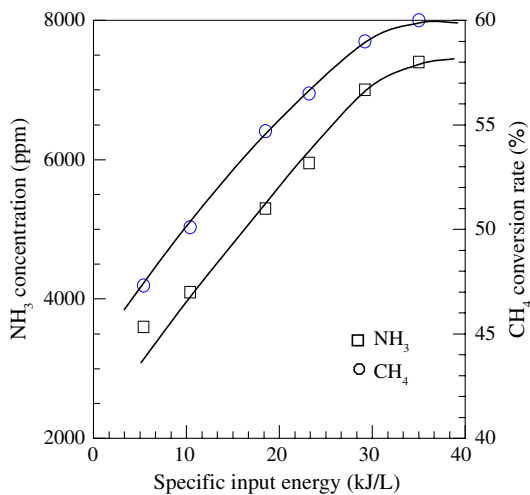
Effect of the Specific Input Energy on the Concentration of Synthesized  $\text{NH}_3$  and Conversion Rate of  $\text{CH}_4$

As shown in Fig. 3, the SIE has a vital effect on the concentration of synthesized  $\text{NH}_3$  and the conversion rate of  $\text{CH}_4$ . The greater the SIE is, the more molecules of  $\text{CH}_4$ ,  $\text{N}_2$  are ionized into activated particles, thus enhancing synthesis of  $\text{NH}_3$ . When the SIE changes in the range of 5.38–29.2 kJ/L, the  $\text{NH}_3$  concentration increases from 3600 ppm to 7000 ppm, meanwhile  $\text{CH}_4$  conversion rate increases from 47.3% to 59.0%. The trend slows after the point where SIE is 29.2 kJ/L. When the SIE is 35 kJ/L, the highest  $\text{CH}_4$  conversion rate of 60.0% is obtained, accordingly the highest  $\text{NH}_3$  concentration is 7400 ppm. However SIE is not further increased due to the possibility of dielectric layer breakdown, in addition, high SIE is also unsuitable for synthesis of  $\text{NH}_3$  from energy consumption perspective.

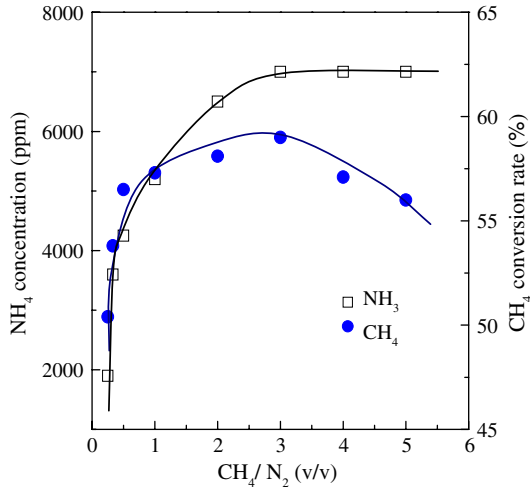
Effect of the Volume Ratio of  $\text{CH}_4$  to  $\text{N}_2$  on the Concentration of Synthesized  $\text{NH}_3$  and Conversion Rate of  $\text{CH}_4$

As shown in Fig. 4, the volume ratio of  $\text{CH}_4/\text{N}_2$  has a strong effect on the concentration of  $\text{NH}_3$ , and the optimum volume ratio is 3:1, where the concentration of  $\text{NH}_3$  and the conversion rate of  $\text{CH}_4$  reach 7000 ppm and 59%, respectively. When the volume ratio of  $\text{CH}_4/\text{N}_2$  is in the range of 0.25~3, the two values increase with the volume ratio. When the ratio of  $\text{CH}_4/\text{N}_2$  exceeds 3, the concentration of  $\text{NH}_3$  remains constant at 7000 ppm, and the conversion rate of  $\text{CH}_4$  decreases with the increase of the volume ratio. The optimum ratio of  $\text{CH}_4/\text{N}_2$  3:1 is the same as that of conventional  $\text{NH}_3$  synthesis process.

**Fig. 3** SIE vs.  $\text{NH}_3$  concentration and  $\text{CH}_4$  conversion.  $Q = 0.5$  L/min;  $\text{CH}_4/\text{N}_2 = 3:1$ ; Gap = 0.64 mm



**Fig. 4** Volume ratio of  $\text{CH}_4/\text{N}_2$  vs.  $\text{NH}_3$  concentration and  $\text{CH}_4$  conversion rate. SIE = 30 kJ/L;  $Q = 0.5 \text{ L/min}$ ; Gap = 0.64 mm

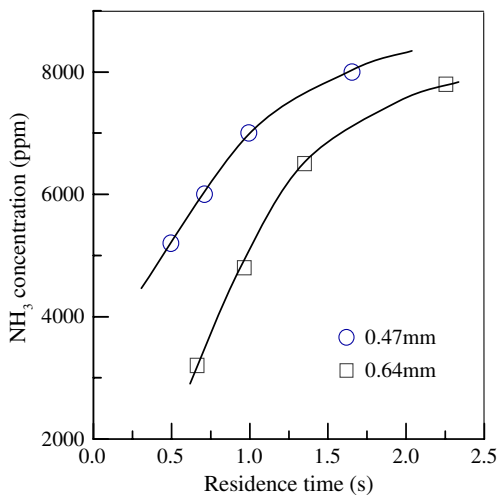


### Effects of the Residence Time and Discharge Gap on the Concentration of Synthesized $\text{NH}_3$

As shown in Fig. 5, curve 1 (0.47 mm) and curve 2 (0.64 mm) for the different discharge gaps have almost the same trend. The concentration of  $\text{NH}_3$  increases with the residence time in the range of 0.5–2.25 s. The residence time is much shorter than that of  $\text{NH}_3$  synthesis by Tanaka et al. [4, 5], because more  $\text{CH}_4$  and  $\text{N}_2$  are ionized and dissociated in our micro-gap discharge.

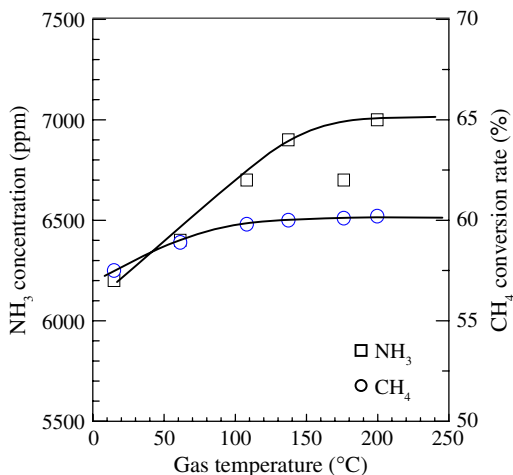
The discharge gap has a great effect on the concentration of  $\text{NH}_3$ . When the residence time is 1.65 s, the concentration of  $\text{NH}_3$  is 6930 ppm for a discharge gap of 0.64 mm, 8000 ppm for a discharge gap of 0.47 mm with a 1070 ppm increase. With the same residence time, the SIE for the discharge gap of 0.47 mm is higher than that of 0.64 mm, so that higher concentration of  $\text{NH}_3$  is obtained with the gap of 0.47 mm. In addition, when

**Fig. 5** Residence time vs.  $\text{NH}_3$  concentration. Discharge power = 240 W;  $\text{CH}_4/\text{N}_2 = 3:1$





**Fig. 6** Gas temperature vs.  $\text{NH}_3$  concentration and  $\text{CH}_4$  conversion rate. SIE = 29.2 kJ/L;  $\text{CH}_4/\text{N}_2 = 3:1$ ;  $Q = 0.5$  L/min; Gap = 0.64 mm



the discharge gap becomes narrow, the fractional active volume is correspondingly increased, resulting in the increase of high-energy electron density. As a result, more molecules of  $\text{CH}_4$  and  $\text{N}_2$  are ionized and dissociated to produce  $\text{N}_2^+$ ,  $\text{NH}$ ,  $\text{CH}_4$ ,  $\text{CH}_3$ -radicals for the synthesis of  $\text{NH}_3$ .

#### Effect of the Gas Temperature on the Concentration of Synthesized $\text{NH}_3$ and Conversion Rate of $\text{CH}_4$

Even though the feed gas isn't heated, its temperature can go up to about 70–80 °C owing to the micro-gap discharge. As shown in Fig. 6, the concentration of  $\text{NH}_3$  increases with the gas temperature in the range of 14.9 ~ 137.3 °C. When the gas temperature exceeds 137.3 °C, the concentration of  $\text{NH}_3$  is almost constant at 7000 ppm. The gas temperature has light effect on the conversion rate of  $\text{CH}_4$ , which is almost constant at 60%. The activation energy of gas molecules increase with the gas temperature so that more  $\text{CH}_4$  and  $\text{N}_2$  are ionized and dissociated for the synthesis of  $\text{NH}_3$ . However, high temperature isn't necessary for synthesis of  $\text{NH}_3$ , and high temperature leads to electrodes breakdown and reactor destruction.

## Conclusions

The conversion of  $\text{CH}_4$  into  $\text{NH}_3$  is investigated using the micro-gap discharge plasma. The whole reaction processes is carried out under the conditions of normal temperature and pressure without any catalyst, which is an environmentally friendly condition in accordance with Green Chemistry Principle. The results show that:

- 1) Analysis of gas ingredient shows that the main products of  $\text{CH}_4/\text{N}_2$  discharge plasma are  $\text{NH}_3$ ,  $\text{H}_2$  and hydrocarbons ( $\leq \text{C}_4$ ) such as  $\text{C}_2\text{H}_6$ ,  $\text{C}_2\text{H}_4$ ,  $\text{C}_2\text{H}_2$ ,  $\text{C}_3\text{H}_8$ ,  $\text{C}_3\text{H}_6$ , *i*- $\text{C}_4\text{H}_{10}$ , *n*- $\text{C}_4\text{H}_{10}$ . The yield and generation rates of hydrocarbons ( $\leq \text{C}_4$ ) are of the following relationship  $\text{C}_2\text{H}_6 > \text{C}_3\text{H}_8 > \text{C}_2\text{H}_2 > \text{C}_2\text{H}_4 > \text{i-C}_4\text{H}_{10}, \text{n-C}_4\text{H}_{10} > \text{C}_3\text{H}_6$ .

- 2) The synthesis of  $\text{NH}_3$  is realized using  $\text{CH}_4/\text{N}_2$  micro-gap discharge at an atmospheric pressure. The yield of  $\text{NH}_3$  is 8000 ppm for a residence time of 1.6 s, and  $1.89 \times 10^3$  mmol/g if the residence time was 2 h.
- 3) The micro-gap gas discharge is a promising method for high  $\text{H}_2$  generation rate in the absence of catalyst. The yield and generation rate of  $\text{H}_2$  are 9.1% (v/v) and 1879.8  $\mu\text{mol}/\text{min}$ , respectively.

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